



Docket No.: 267410US26PCT

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313



ATTORNEYS AT LAW

RE: Application Serial No.: 10/527,642
Applicants: Masanobu IGETA, et al.
Filing Date: March 14, 2005
For: METHOD FOR FORMING INSULATING FILM ON
SUBSTRATE, METHOD FOR MANUFACTURING
SEMICONDUCTOR DEVICE AND SUBSTRATE-
PROCESSING APPARATUS
Group Art Unit: 2812
Examiner: Cheung LEE

SIR:


Attached hereto for filing are the following papers:

Response and Provisional Election

Our credit card payment form in the amount of \$0.00 is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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